



Sheet 1 of 1

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APPLICANT(S): Johann Engelhardt and Frank Schreiber

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UNITED STATES PATENT DOCUMENTS

EXAM. INITIAL		DOCUMENT NUMBER	DATE	INVENTOR	CLASS	SUB CLASS	FIL. DATE IF APPR
Ⓒ	AA	5,868,675	Feb 9 1999	Henrion, et al.	600	424	

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		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRAN Y/N
*Ⓒ	BA	WO 95/19552	20 July 1995	PCT	G01J	1/20	Y
*Ⓒ	BB	WO 98/28655	2 July 1998	PCT	G02F		Y
*Ⓒ	BC	JP 11183806	9 July 1999	Patent Abstracts of Japan	G02B	21/00	Y (Abstract Only)
*Ⓒ	BD	DE 19654211 A1	13 Aug 1998	DE	G02B	21/00	N
Ⓒ	BE	DE 69022063 T2	13 June 1996	DE	A61B	19/00	U.S. Counter- part

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*Ⓒ	CA	"Scanned Probe Microscope Workstation", XP 000588089, IBM Technical Disclosure Bulletin, Vol. 38, No. 12, December 1995, pp. 117-122.
*Ⓒ	CB	Trepte, Oliver, et al., "Computer Control for a Galvanometer Scanner in a Confocal Scanning Laser Microscope", XP 000475121, Optical Engineering, November 1994, Vol. 33, No. 11, pp. 3774-3780.
*Ⓒ	CC	Moore, C.J.L., et al., "A Spatially Resolved Spectrally Resolved Photoluminescence Mapping System", Journal of Crystal Growth, 103 (1990) June 11, Nos. 1/4, Amsterdam, NL, pp. 21-27.
*Ⓒ	CD	"Lichtstrermikroskopie zur flächigen Beurteilung von Oberflächen", XP 000312362, Microtechnic (1992) No. 3, Zurich, CH, pp. 28-31.
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